

L Number	Hits	Search Text	DB	Time stamp
1	73727	electron adj2 (source gun apparatus device)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 09:16
2	5146	photocathode	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:51
3	46739	electromagnetic adj2 (radiation irradiation)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:52
4	80979	lithograph\$2	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:52
5	1626535	substrate	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:53
6	524804	modulat\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:52
7	1087	(electron adj2 (source gun apparatus device) ) and lithograph\$2 and modulat\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:53
8	8864	(electron adj2 (source gun apparatus device) ) and modulat\$3 and modulat\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:53
9	4574	(electron adj2 (source gun apparatus device) ) and substrate and modulat\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:53
10	157613	substrate with pattern	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:53
11	963	(electron adj2 (source gun apparatus device) ) and (substrate with pattern) and modulat\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:53
12	310	((electron adj2 (source gun apparatus device) ) and lithograph\$2 and modulat\$3) and ((electron adj2 (source gun apparatus device) ) and (substrate with pattern) and modulat\$3)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:53

13	1060	(electron adj2 (source gun apparatus device) ) and (((electromagnetic adj2 (radiation irradiation)) laser) with lens)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 10:23
15	3043617	thermostat temperature	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 10:06
17	6580	(electron adj2 (source gun apparatus device) ) and (photocathode (electromagnetic adj2 (radiation irradiation)) laser) and (thermostat temperature)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:55
16	34	((((electron adj2 (source gun apparatus device) ) and lithograph\$2 and modulat\$3) and ((electron adj2 (source gun apparatus device) ) and (substrate with pattern) and modulat\$3)) and ((electron adj2 (source gun apparatus device) ) and (((electromagnetic adj2 (radiation irradiation)) laser) with lens))) and (thermostat temperature)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 08:55
14	49	((((electron adj2 (source gun apparatus device) ) and lithograph\$2 and modulat\$3) and ((electron adj2 (source gun apparatus device) ) and (substrate with pattern) and modulat\$3)) and ((electron adj2 (source gun apparatus device) ) and (((electromagnetic adj2 (radiation irradiation)) laser) with lens)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 09:06
18	15	((((electron adj2 (source gun apparatus device) ) and lithograph\$2 and modulat\$3) and ((electron adj2 (source gun apparatus device) ) and (substrate with pattern) and modulat\$3)) and ((electron adj2 (source gun apparatus device) ) and (((electromagnetic adj2 (radiation irradiation)) laser) with lens))) not (((electron adj2 (source gun apparatus device) ) and lithograph\$2 and modulat\$3) and ((electron adj2 (source gun apparatus device) ) and (substrate with pattern) and modulat\$3)) and ((electron adj2 (source gun apparatus device) ) and (((electromagnetic adj2 (radiation irradiation)) laser) with lens))) and (thermostat temperature))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 09:06
19	185752	electron adj2 (source gun apparatus beam device)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 09:16
20	158	lithograph\$2 and (electron adj2 (source gun apparatus beam device) ) and photocathode	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 09:17
21	56	(lithograph\$2 and (electron adj2 (source gun apparatus beam device) ) and photocathode ) and modulat\$3	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 09:16
22	74	(lithograph\$2 and (electron adj2 (source gun apparatus beam device) ) and photocathode ) and (thermostat temperature)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 09:17
24	5	lithograph\$2 and (electron adj2 (source gun apparatus beam device) ) and (photocathode with (thermostat temperature))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 09:17
25	3	("3757151"   "4060823"   "5684360").PN.	USPAT	2003/08/28 09:34
26	6	("4460831"   "4820927"   "4868380"   "4906894"   "4970392"   "5039862").PN.	USPAT	2003/08/28 09:35
27	16	5684360.URPN.	USPAT	2003/08/28 09:36

28	1	6376984.URPN.	USPAT	2003/08/28 09:36
29	25	4460831.URPN.	USPAT	2003/08/28 09:55
23	192	photocathode with (thermostat temperature)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 10:02
30	1	thermostat with photocathode	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 10:04
31	0	551620.URPN.	USPAT	2003/08/28 10:06
32	10	(control\$4 near5 temperature) with photocathode	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 10:10
33	176	((control\$4 near5 temperature) with cathode) and (electron adj2 (source gun apparatus device) )	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 10:11
34	28	((control\$4 near5 temperature) with cathode) and (electron adj2 (source gun apparatus device) ) ) and ((electromagnetic adj2 (radiation irradiation)) laser)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2003/08/28 10:23